

#### >>> DELIVER FOR BETTER PVD PROCESSES



# INTRODUCTION TO V-Grade 5S Software V-Grade 5S V-Grade 5S Plus V-Grade 5S Pro

### FACT Few PVD Processes Are Optimized

#### <u>3 FUNDAMENTAL MEASURES OF A PVD PROCESS</u>

- Deposition rate
  - it often determines the throughput
- Vapor capture
  - percentage of material vapor captured by the workpiece carrier, a measure of efficient use of source materials
- Thickness distribution
  - it determines if specs are met, and therefore yield

\*Emphasis may be different from one job to another

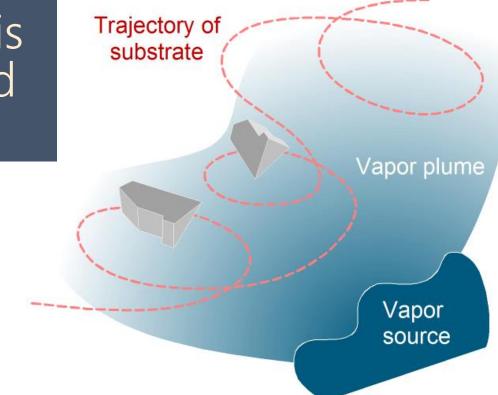




### FACT PVD Processes Are Convoluted

Realistic numerical simulation is essential to achieving a desired outcome.

*V-Grade 5S* series software was conceived to fulfil the needs.





#### V-GRADE 5S SERIES SOFTWARE IS BUILT TO ADDRESS CRITICAL NEEDS IN

- Design of PVD equipment
- Optimize and debug PVD processes
- Feasibility studies
- Specification development
- Production planning
- Cost analysis (material & power consumptions)





#### (cont') WHERE YOU MAY ENCOUNTER

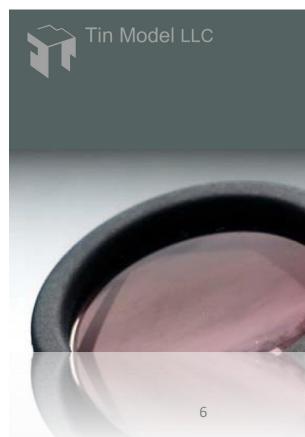
- Common or specialty source types
- Source re-position and re-orientation
- Vapor obstruction (masks, baffles, chimneys, dividers and collimators)
- Novel substrate motion
- Multiple-source deposition
- Power-modulated transits
- Complex-surface substrates
- Plasma enhanced processes, such as HiPIMS
   >> and a lot more

#### "NO PROCESS IS TOO DIFFICULT OR TOO COMPLEX"



### DESIGN PRINCIPLE OF V-GRADE 5S SOFTWARE **Power and Ease-of-Use**

- Rich in features yet intuitive
- Graphic user interface
- Libraries of common sources and substrates
- Enablement of unconventional processes
- Example configurations for quick starts
- Spreadsheet compatibility (imports and exports)
- Standardized file handling

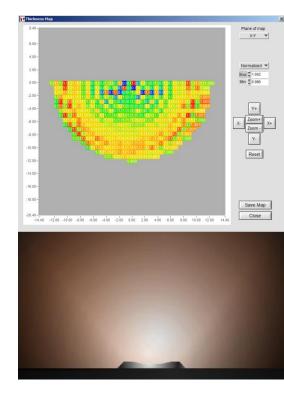




## V-GRADE 55 COMPUTATION ENGINE Accurate, Reliable and Fast

Our clients have employed *V-Grade 5S* series software to design and build some of the most complicated and mission-critical PVD processes.

With *V-Grade 5S*, novel solutions have been discovered, tested and verified.





### V-GRADE 5S SERIES SOFTWARE ENABLES **PVD Engineering for Sustainability**

Not all PVD processes are equal in their impact to the environment and consumption of natural resources. V-Grade 5S makes it easy to maximize a figure of merit :

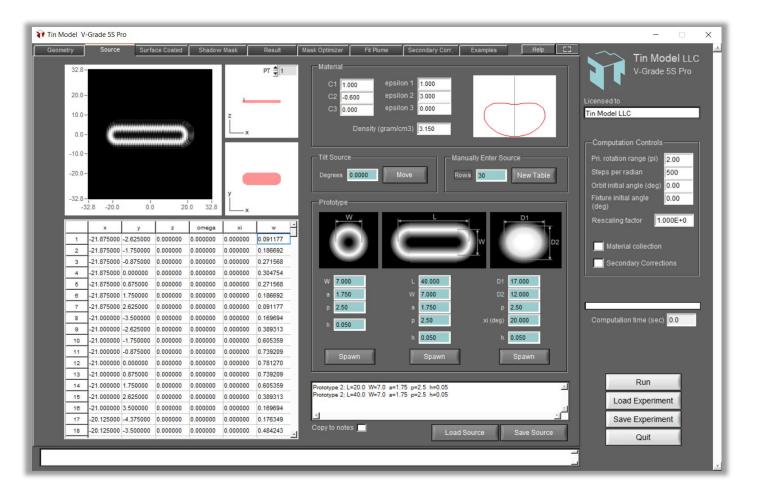
#### $M = R \cdot V \cdot (1 - NU) / W$

where R is deposition rate, V vapor capture, W power applied to the source, and NU non-uniformity, all of which are quantifiable within V-Grade 5S. The higher the M the better a process conserves raw materials and energy, thus more environmentally plausible.





# V-Grade 5S series features: SOURCE



#### Source types

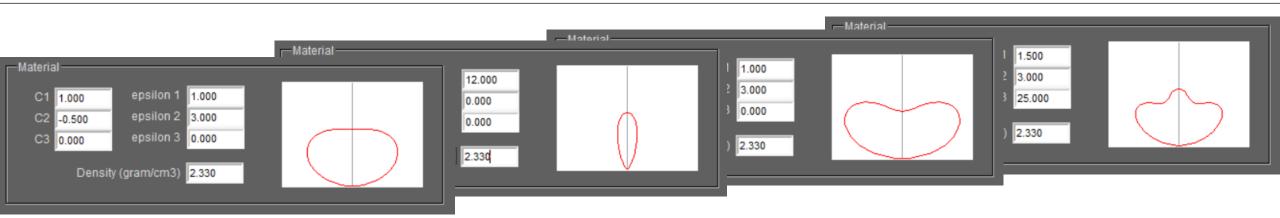
- Evaporation
- Magnetron sputtering
- Ion-beam sputtering
- Uncommon-geometry sources
- Laser ablation
- Cylindrical magnetron
- User-defined arbitrary

#### Source positioning

• Tiltable 360 degrees



# V-Grade 5S series features: VAPOR PLUME



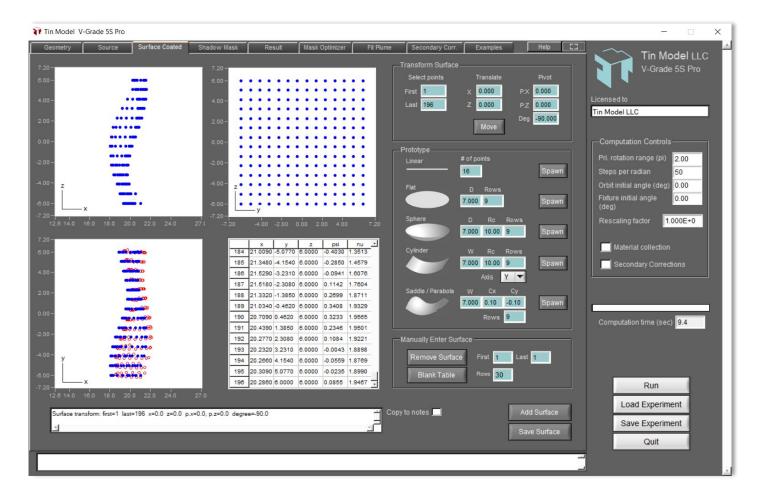
Vapor plume handling: definable with a 3-term expression that encompasses

- Evaporation
- Sputtering

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- Plume evolution due to target erosion
- Tilt axis (ion-beam sputtering)
- Fit to experimental data (via an automated routine)

# V-Grade 5S series features: SUBSTRATE



Substrate types

• Flat

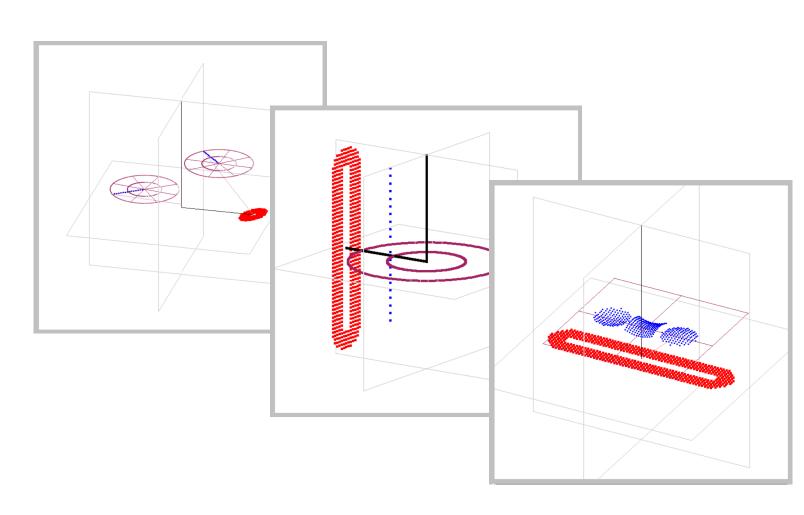
- Spherical
- Aspherical
- Parabolic
- Cylindrical
- Saddle
- User-defined arbitrary

### Substrate repositioning

• Translate & tilt



## V-Grade 5S series features: SUBSTRATE MOTION

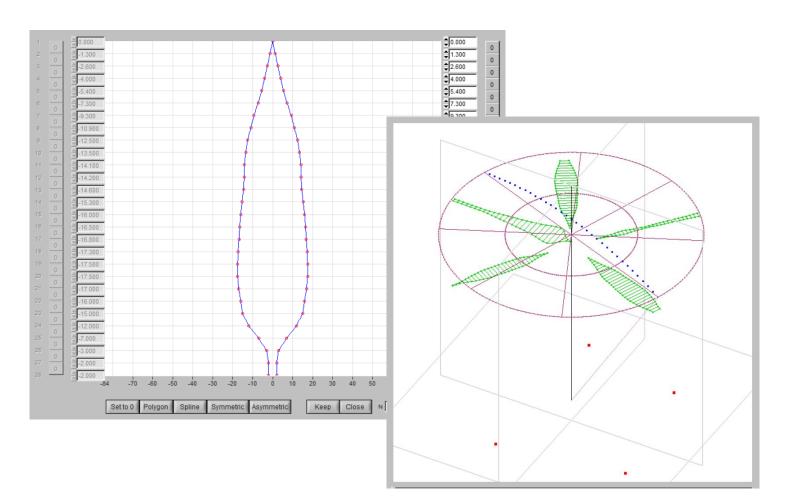


Motion types

- 1-axis rotation
- 2-axis rotation (planetary)
- 3-axis rotation
- Linear translation
- Roll-to-roll
- User-defined arbitrary



# V-Grade 5S series features: VAPOR OBSTRUCTION



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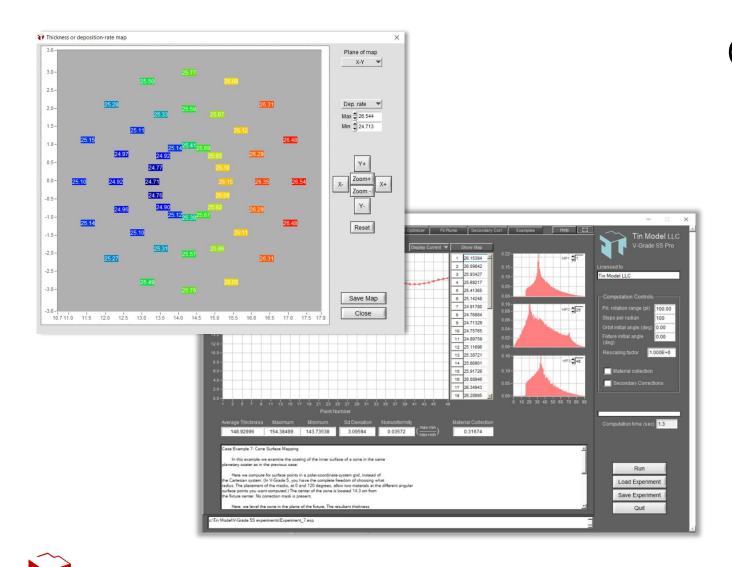
Shadow masks

Symmetrical Asymmetrical Arbitrary shapes Mounting provisions Positive & negative Static & rotational Tiltable Automatic optimization

- Baffles
- Dividers
- Collimators

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# V-Grade 5S series features: RESULT



#### Output

- Thickness plot & maps
- Deposition-rate plot & maps
- Power requirement for given deposition rates
- Vapor capture %
- Vapor-striking-angle statistics
- Optimized masks
- Mask manufacturing files
- Vapor plume functions
- Dynamic 3D representation

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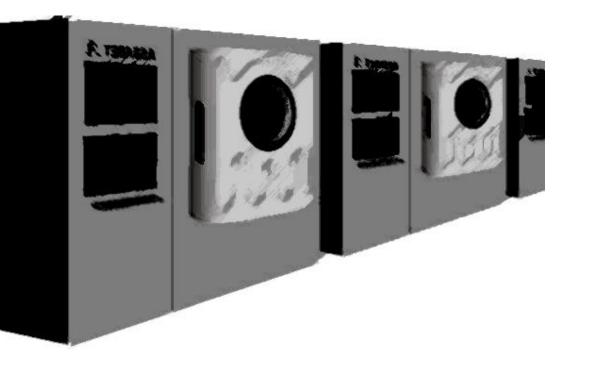
# V-Grade 5S series features: DEPOSITION RATE

Teposition Rate Calculator					X	×
✓ Magnetron sputtering         67.350       Molecular mass (e.g. 108 for Ag; 47.9 for Ti)         1.250       Sputtering yield (e.g. 3.2 for Ag; 0.8 for Ti)         1000.0000       Power applied (W)         □ DC       ✓ RF	Ion-beam sputtering81.400Molecular mass (e.g. 197 for Au; 28.1 for Si)2.500Sputtering yield (e.g. 4.2 for Au; 1.63 for Si)1.0000Ion energy (keV)500.0000Ion current (mA)	Evaporation         1300.000       Vapor pressure at 2000K (Pa) (e.g. 1300 for SiO2; 5 for Ti)         0.200       Process merit (e.g. 0.1 for typical; 0.5 for high)         5.0000       Power applied (kW)	Rotational or stationary     Linear translation     Roll-to-roll     Display: nm/minute	Substrate velocity (cm/min) Substrate velocity (cm/min) Save	5.873         5.861         5.853         5.854         5.863         5.877           5.812         5.767         5.771         5.769         5.783         5.811         5.849         5.878           5.747         5.723         5.776         5.696         5.699         5.723         5.771         5.811         5.811         5.811         5.811         5.811         5.811         5.811         5.811         5.811         5.878           5.747         5.723         5.771         5.696         5.699         5.723         5.771         5.811         5.874           5.722         5.711         5.697         5.658         5.692         5.760         5.886           5.745         5.754         5.713         5.658         5.633         5.641         5.695         5.784         5.880           5.797         5.828         5.925         5.711         5.645         5.613         5.651         5.739         5.835           5.849         5.898         5.936         5.666         5.614         5.629         5.710         5.816	Plane of map X-Y V Max $\oint 5.929$ Min $\oint 5.614$ Y+
Deposition Rate Calculator available for • Magnetron sputtering						X- Zoom+ Y- Reset
<ul><li>Ion-beam sputtering</li><li>Evaporation</li></ul>				-225- -2250- -2.75- -3.00- -3.23- 11.1 11.5 12.0 12.5	5791 5757 5732 5715 5705 5707 5730 5777 5836 5879 5852 5821 5796 5781 5776 5791 5819 5855 5883 5891 5882 5870 5862 5883 5871 5884 13.0 13.5 14.0 14.5 15.0 15.5 16.0 16.5 17.0 17.5	Save Map Close
<ul> <li>Any geometric configuration</li> </ul>				[	Deposition-rate map	

• Final thickness in the case of linear-translation or roll-to-roll coating

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# V-Grade 5S series features: SECURE OPERATIONS



V-Grade 5S series software treats your data security as a priority. At no time your data are exposed to external risks.

- 100% self-contained programs operate off-line
- Installs off-line
- Your IP and sensitive information are unexposed to risks



With *V-Grade 5S* series software, you can solve problems from the mundane to the most challenging: NO PROCESS IS TOO DIFFICULT OR TOO COMPLEX

#### "TURN YOUR IDEAS INTO PRACTICAL AND WINNING PVD PROCESSES"



NOT ALL PVD PROCESSES ARE EQUAL: CHOOSE SUSTAINABILITY !





#### >>> DELIVER FOR BETTER PVD PROCESSES



## FOR FURTHER INFORMATION CONTACT US info@tinmodel.com www.tinmodel.com Ph. 857.498.9723